

Docket No.: 49657-961

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IDS
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kenji ITOGA, et al.

Serial No.:

Group Art Unit:

Filed: January 26, 2001

Examiner:

For: X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK, X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON RADIATION METHOD AND SEMICONDUCTOR DEVICE



INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, DC 20231

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached form PTO-1449. It is respectfully requested that the references be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

A copy of the International Search Report and cited references are attached for the Examiner's information.

Serial No.:

Additional references are also attached.

Respectfully submitted,

MCDERMOTT, WILL & EMERY

A handwritten signature in black ink, appearing to read "S. Becker", written over a horizontal line.

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